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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Sujit Sharan and Gurtej S. Sandhu

Serial No.: 09/825,613

Filed: April 3, 2001

For: METHOD FOR PECVD DEPOSITION OF SELECTED  
MATERIAL FILMS

§  
§ Group Art Unit: 2829  
§  
§ Examiner: Lisa A Kilday  
§  
§ Atty. Docket: 95-0716.03  
§  
§  
§

2829  
J.B.  
J. Steptae  
6-24-02  
RECEIVED  
JUN 14 2002  
TECHNOLOGY CENTER 2800

FIRST AMENDMENT AND RESPONSE TO THE OFFICE ACTION OF MARCH 7, 2002

Commissioner for Patents  
Washington, D.C. 20231

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6/6/02  
Date

*Susan Jerome*  
Signature

Dear Sir:

Applicants herein respond to the Office Action of March 7, 2002. Please amend the above-captioned application as follows.

IN THE SPECIFICATION:

Please amend the following Specification paragraphs to the form described below.

31 [0000] This application is a continuation of application serial number 09/249,478, filed Feb. 12, 1999 and issued as U.S. Pat. No. 6,291,341.

[0027] For the purposes of describing one particular embodiment of the invention, it is assumed that a deposition process is to be carried out within the PECVD system 10 described in